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TRANSMITTAL FORM (to be used for all correspondence after initial filing)	Application Number	10/664,738
	Filing Date	09/18/2003
	First Named Inventor	Janos Fucsko
	Art Unit	1763
	Examiner Name	Unknown
	Attorney Docket Number	MI22-2271
Total Number of Pages in This Submission		

ENCLOSURES (Check all that apply)		
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SIGNATURE OF APPLICANT, ATTORNEY, OR AGENT	
Firm or Individual name	Mark S. Matkin, Reg. No. 32,268 Wells St. John P.S.
Signature	
Date	12/31/03

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EL 979951384

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application Serial No. 10/664,738
Filing Date September 18, 2003
Inventor Fucsko et al.
Assignee Micron Technology, Inc.
Group Art Unit 1763
Examiner Unknown
Attorney Docket No. MI22-2271
Title: Methods of Etching Silicon Nitride Substantially Selectively Relative to an
Oxide of Aluminum and Methods of Forming Trench Isolation Within a
Semiconductor Substrate



SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References - See Attached Form PTO-1449


In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. Copies of the cited art are attached hereto. No admission is made regarding whether all the submitted references are prior art.


This Supplemental Information Disclosure Statement is being filed within three months of the filing date of the application or before the mailing of a first Office Action on the merits, whichever occurs last. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee specified under 37 C.F.R. § 1.17(p) to Deposit Account No. 23-0925.

Respectfully submitted,

Dated: 12-31-03

By: 
Mark S. Matkin
Reg. No. 32,268

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2271	SERIAL NO. 10/664,738		
 <p style="text-align: center;">LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)</p>				APPLICANT: Micron Technology, Inc.			
				FILING DATE September 18, 2003	GROUP 1763		
U.S. PATENT DOCUMENTS							
*Examiner's Initials		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
	AJ						
	AK						
	AL						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AM		B. Garrido et al., "The Role of Chemical Species in the Passivation of <100> Silicon Surfaces by HF in Water-				
			Ethanol Solutions", J. Electrochem. Soc., Vol. 143, No. 12, December 1996, pp. 4059-4066.				
	AN		Wood et al., "Etching Silicon Nitride and Silicon Oxide Using Ethylene Glycol / Hydrofluoric Acid Mixtures",				
			Electrochemical Society Proceedings Volume 99-36, pp. 258-263.				
	AO		Knotter et al., "Etching Mechanism of Silicon Nitride in HF-Based Solutions", J. Electrochem. Soc., 148 (3),				
			2001, pp. F43-F46.				
EXAMINER		DATE CONSIDERED					
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>							

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	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
	AJ						
	AK						
	AL						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AM		T. Kezuka et al., "The Control of Etching Rate for Various SiO ₂ Films", Electrochemical Society Proceedings,				
			Vols. 99-36, 2000, pp. 244-251.				
	AN						
	AO						
EXAMINER		DATE CONSIDERED					
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>							